

FIG. 1

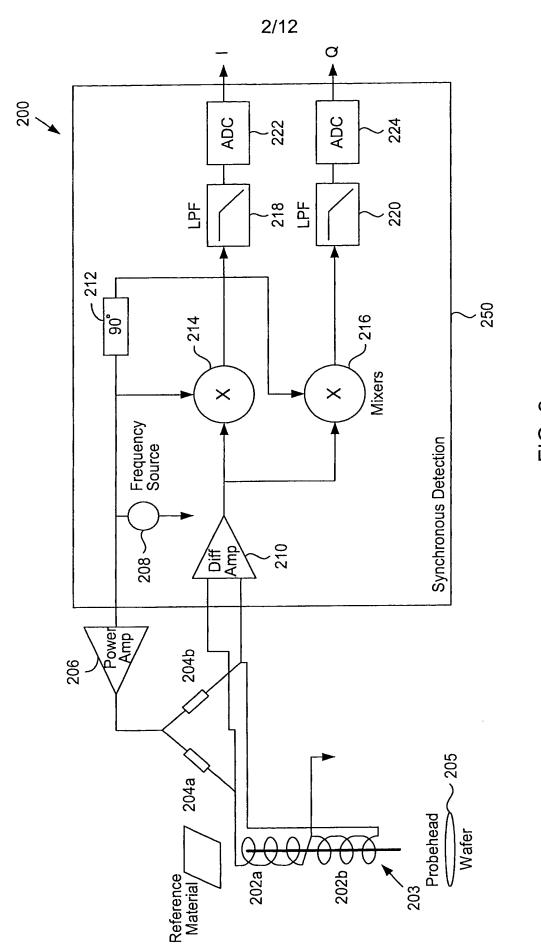


FIG. 2

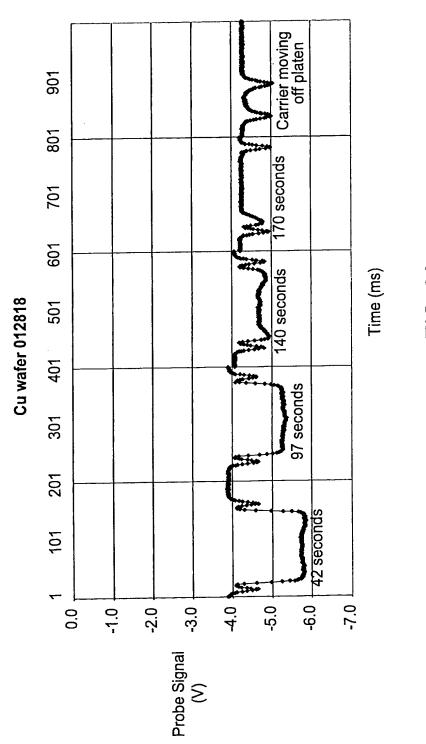
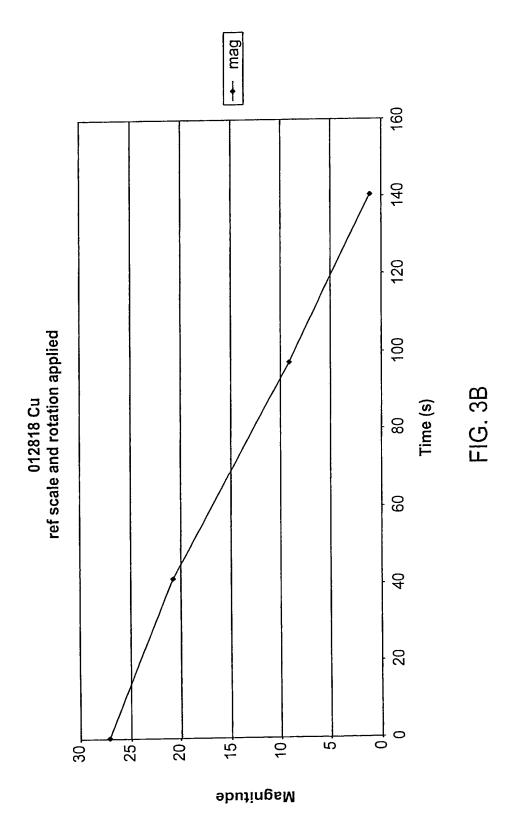


FIG. 3A



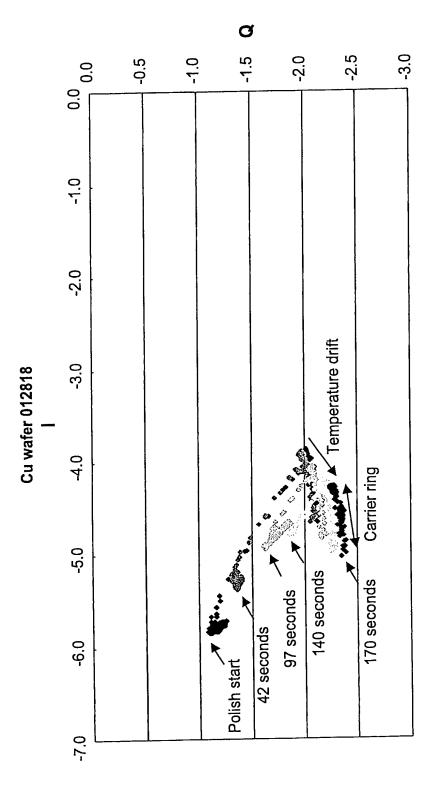
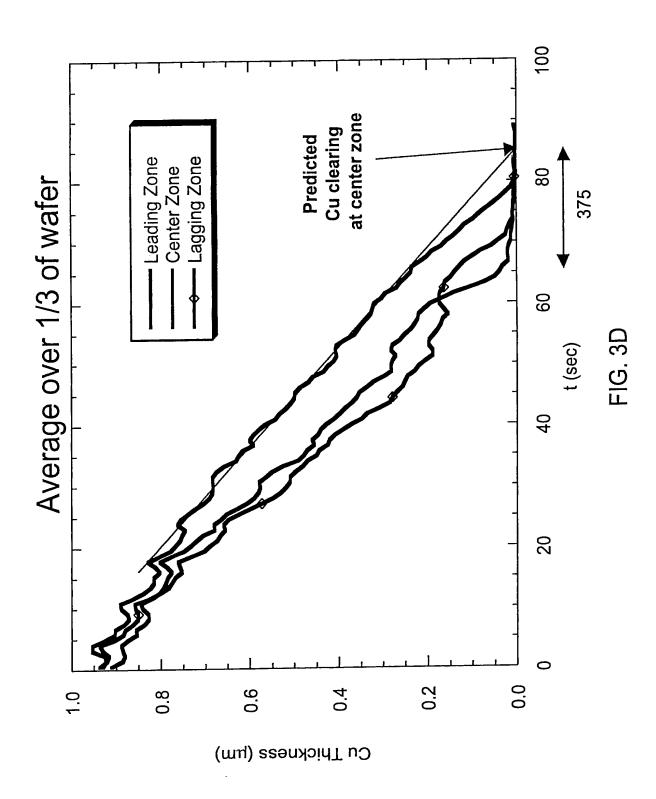


FIG. 30



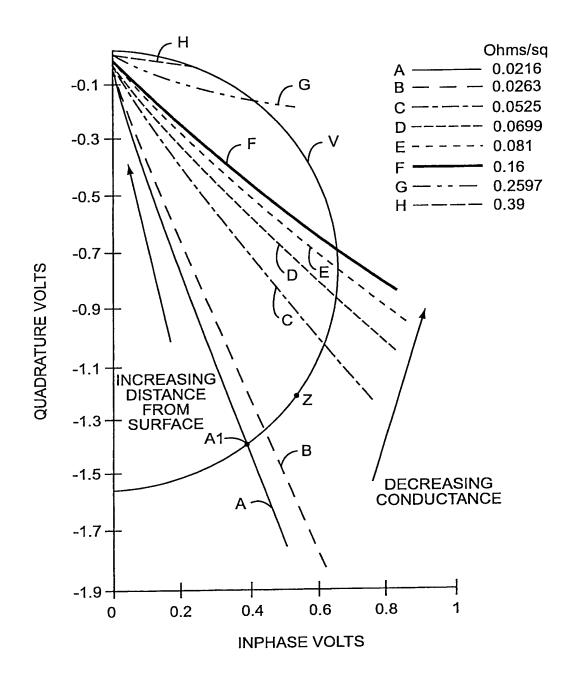
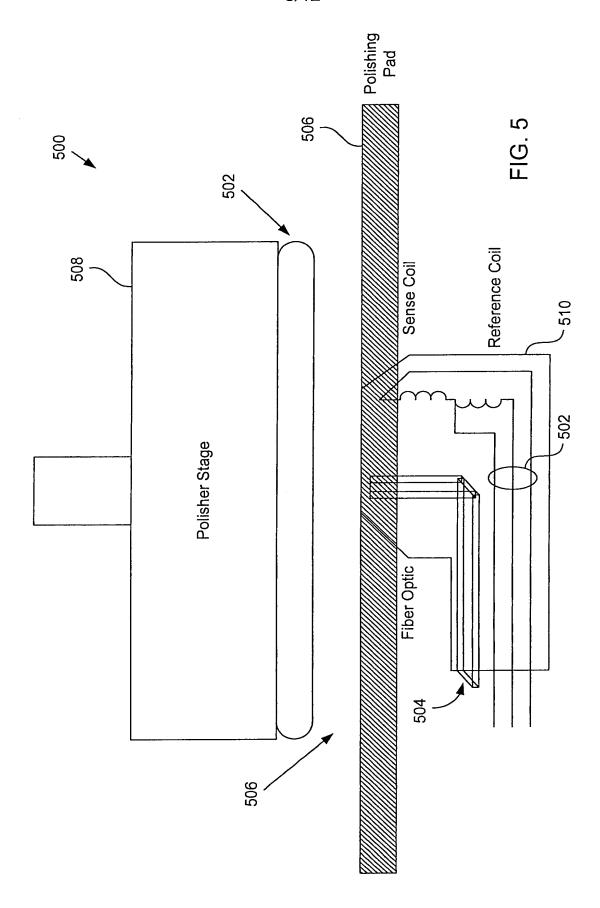


FIG. 4



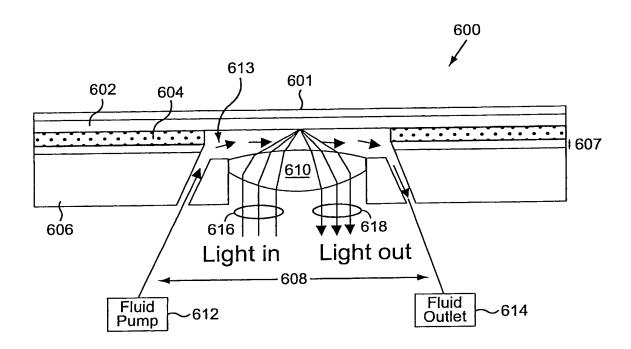
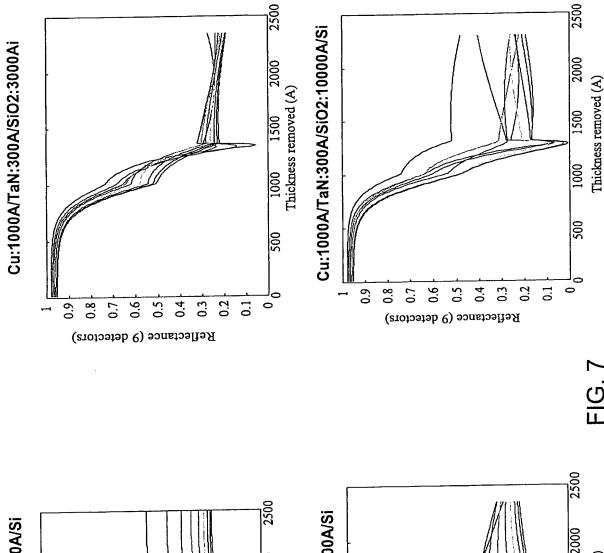


FIG. 6



Cu:1000A/TaN:300A/SiO2:4000A/Si Cu:1000A/TaN:300A/SiO2:1000A/Si 2000 Thickness removed (A) Thickness removed (A) 1500 1500 8 0.2 0.8 0.7 0.2 0.1 0.9 9.4 0.3 0.8 9.0 0.5 0.7 Reflectance (9 detectors) Reflectance (9 detectors)

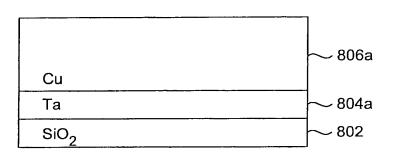
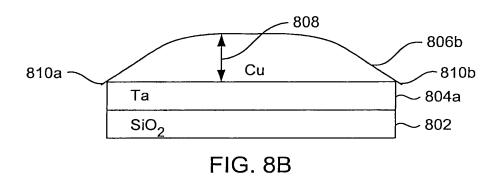
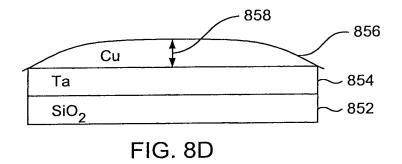


FIG. 8A



810a Cu 806c 810b Ta 804b SiO₂ 802

FIG. 8C



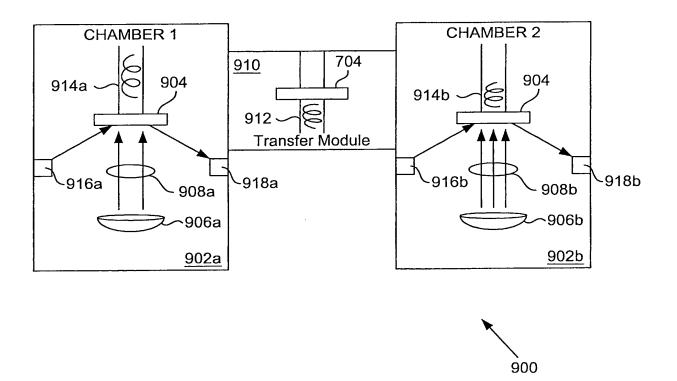


FIG. 9